



UNIVERSIDADE ESTADUAL PAULISTA  
"JÚLIO DE MESQUITA FILHO"  
Campus de São José do Rio Preto

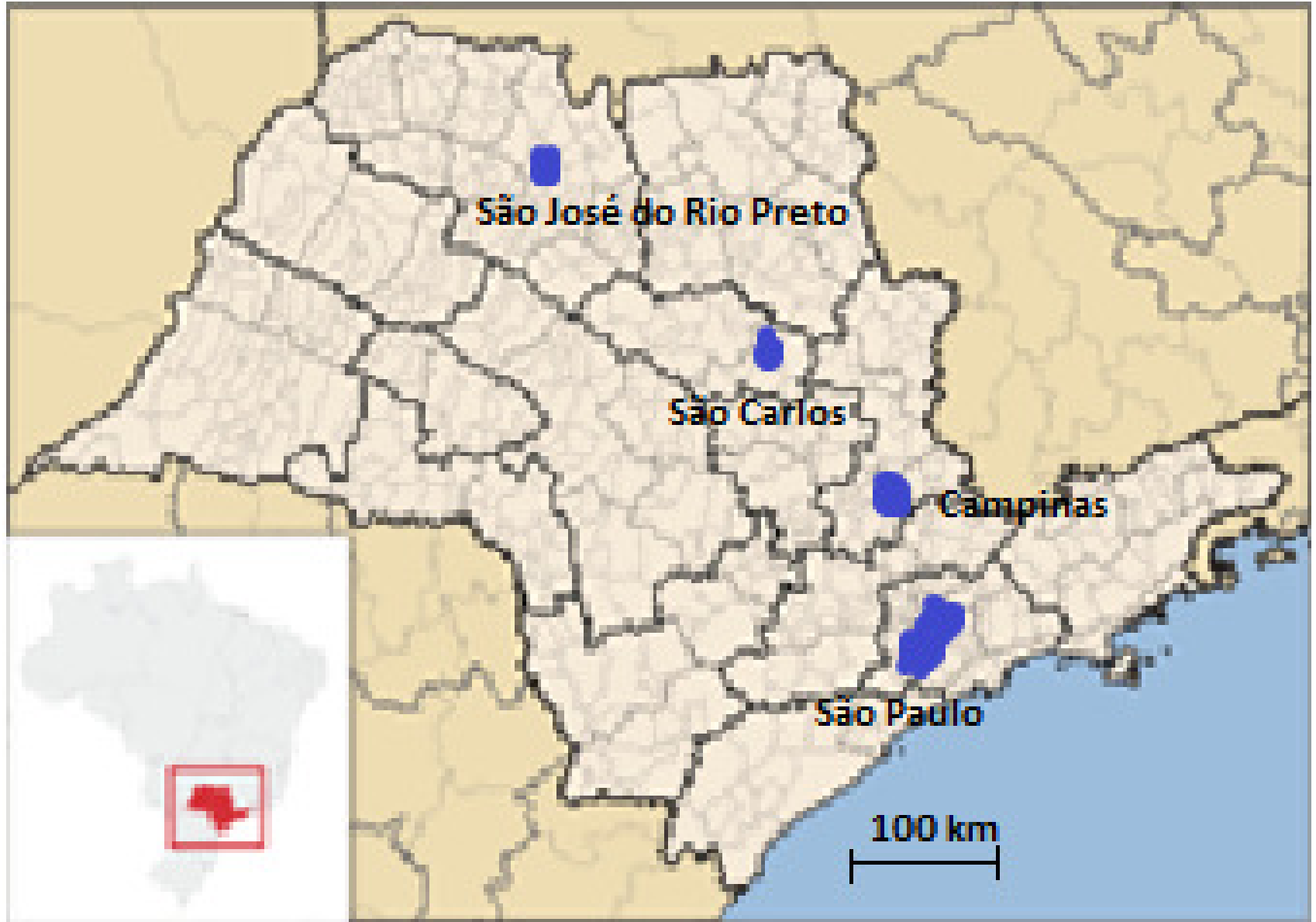
# Flexible, Transparent thin-film transistors for display technology

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# Summary

- Thin film transistors (TFTs) using solution-processed metal-oxides as active material;
- Applications on active-matrix displays (AMD);
- Current demand on AMDs;
- Conclusions and Perspectives;



# Laboratório de Optoeletrônica Orgânica – DF/IBILCE/UNESP



# Topics of interest

## **Electronic transport in Organic Semiconductors**

- Sandwich structures: OLEDs and OPVs;
- Planar structures: OFETs and biosensors;
- a.c. and d.c. electrical characterization (impedance spectroscopy,  $I_xV$ , electroluminescence, electroabsorption, etc.);

## **Thin-film transistors comprising solution-processed amorphous metal oxides (AMOs):**

- Transparent devices for applications on active-matrix displays;
- Solution-processed. Precursor route. Nanoparticles;
- Electrical transport properties on AMOs;

# Motivation: Transparent active-matrix display



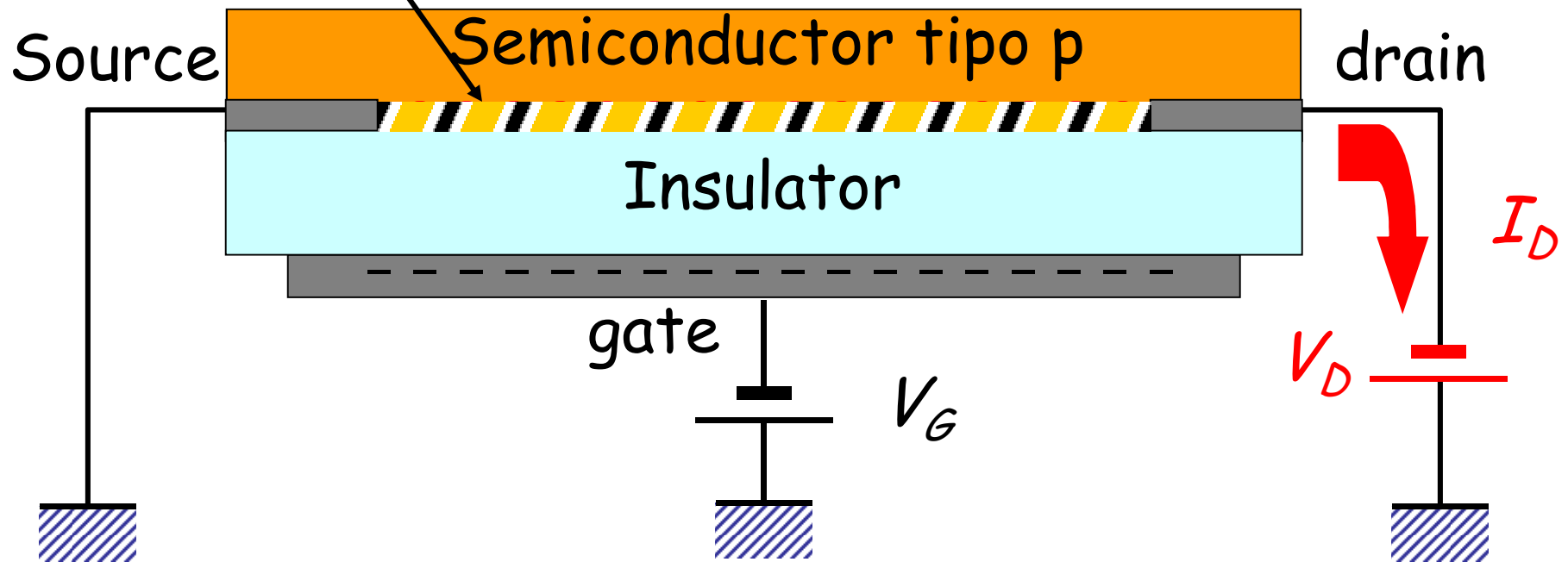
## Motivation: Transparent active-matrix display

- Requirements for flexible transparent displays:
  - High transmittance of the materials in the visible spectrum range (for the materials that composes the pixel and the drive circuit);
  - Compactibility with flexible substrates (low-temperature deposition);
  - Coverage of large areas, low-cost and processability;

# Thin-film Transistors (TFTs)

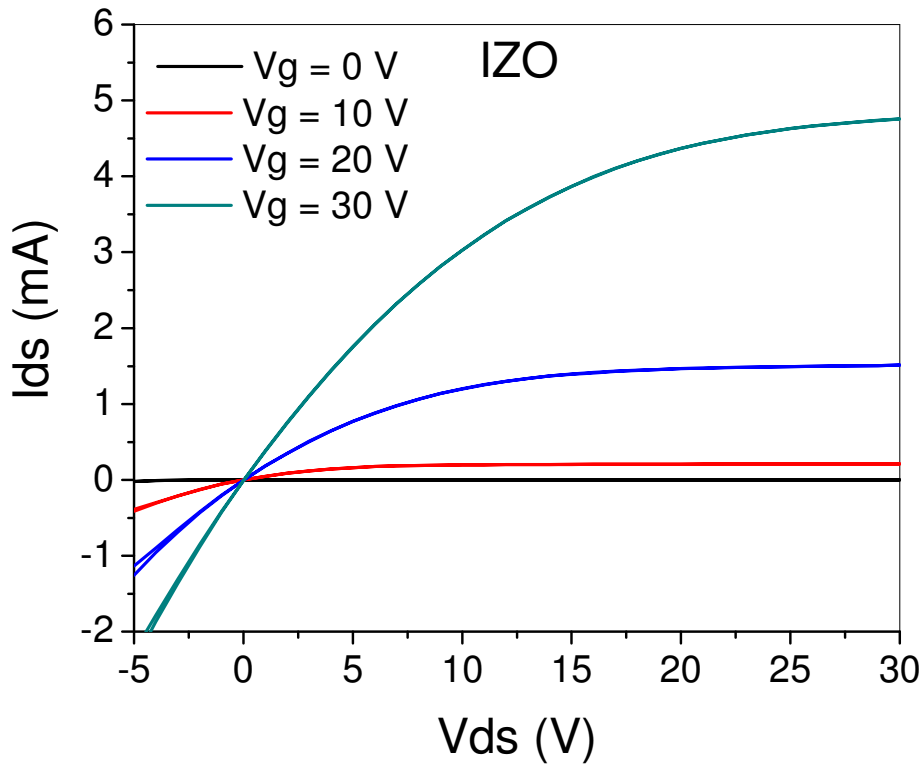
Enhancement type TFT  
(*accumulation*)

Conducting channel

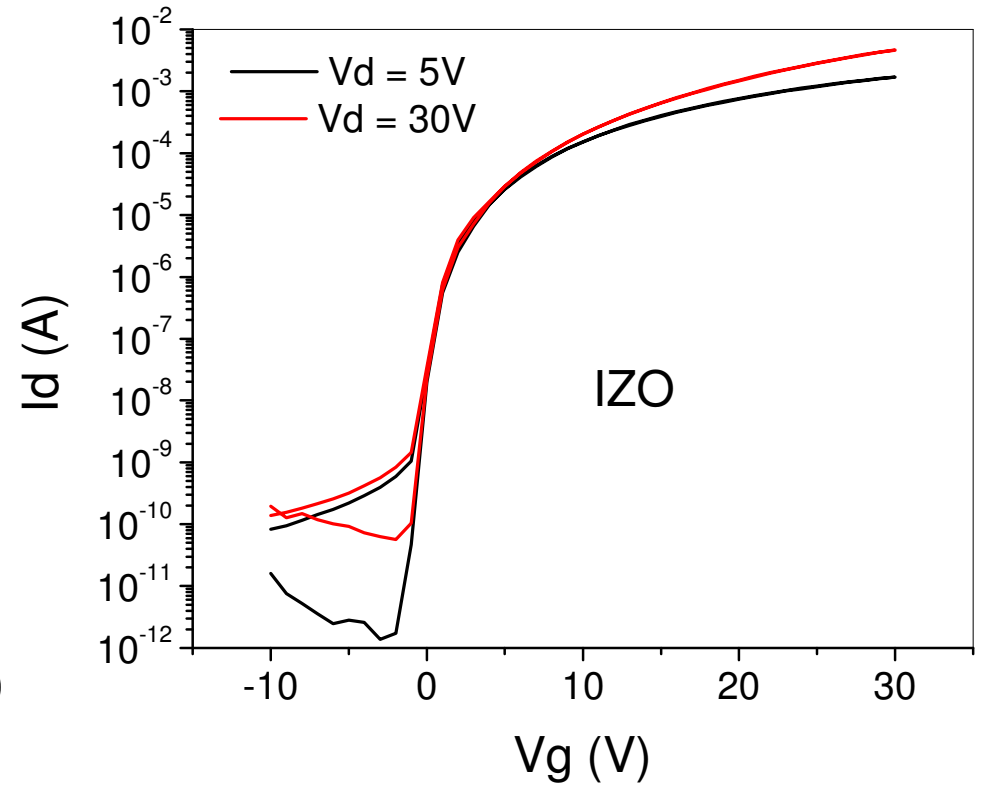




# Thin-film Transistors (TFTs)



*Output curve*



*Transfer curve*

# FETs: Modo de Operação e Princípios Básicos

Substituindo e integrando em  $x$  :

$$I_D = \frac{LC_i\mu}{W} \left[ (V_G - V_T)V_{DS} - \frac{V_{DS}^2}{2} \right] \quad \text{Shockley equation for a TFT}$$

$I_D$ : corrente no dreno (canal)

$V_G$ : Tensão no *gate*

$V_{DS}$ : Tensão dreno-fonte

$W$ : largura do canal

$L$ : comprimento do canal

$C_i$ : Capacitância por unidade de área do dielétrico

$\mu$ : mobilidade dos portadores no canal

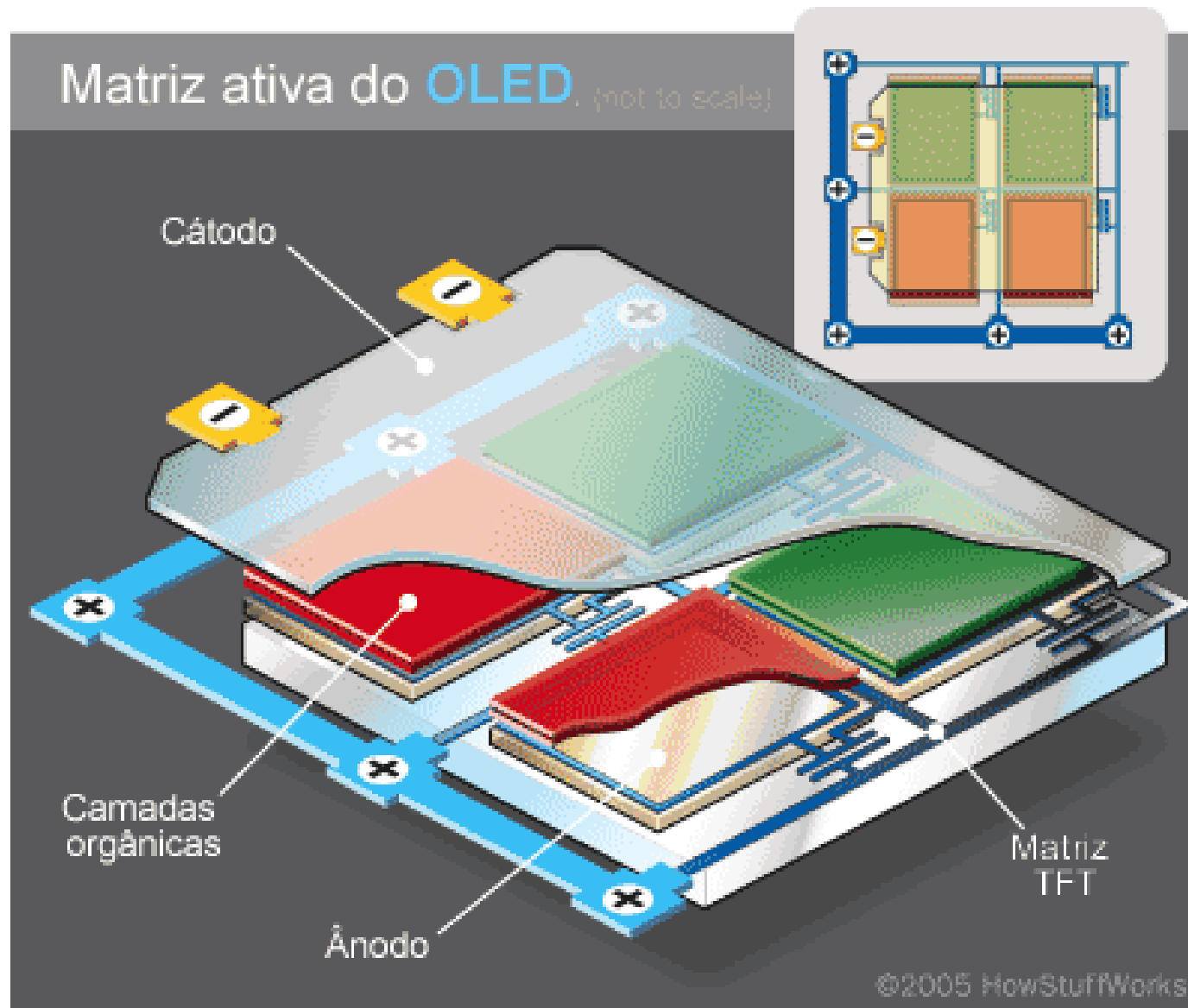
Válida para:  $0 \leq V_{DS} \leq (V_G - V_T)$  Até o “joelho” da curva de saída

# Transistores de Efeito de campo (FETs)

**Parâmetros importantes obtidos a partir das curvas de saída e de transferência:**

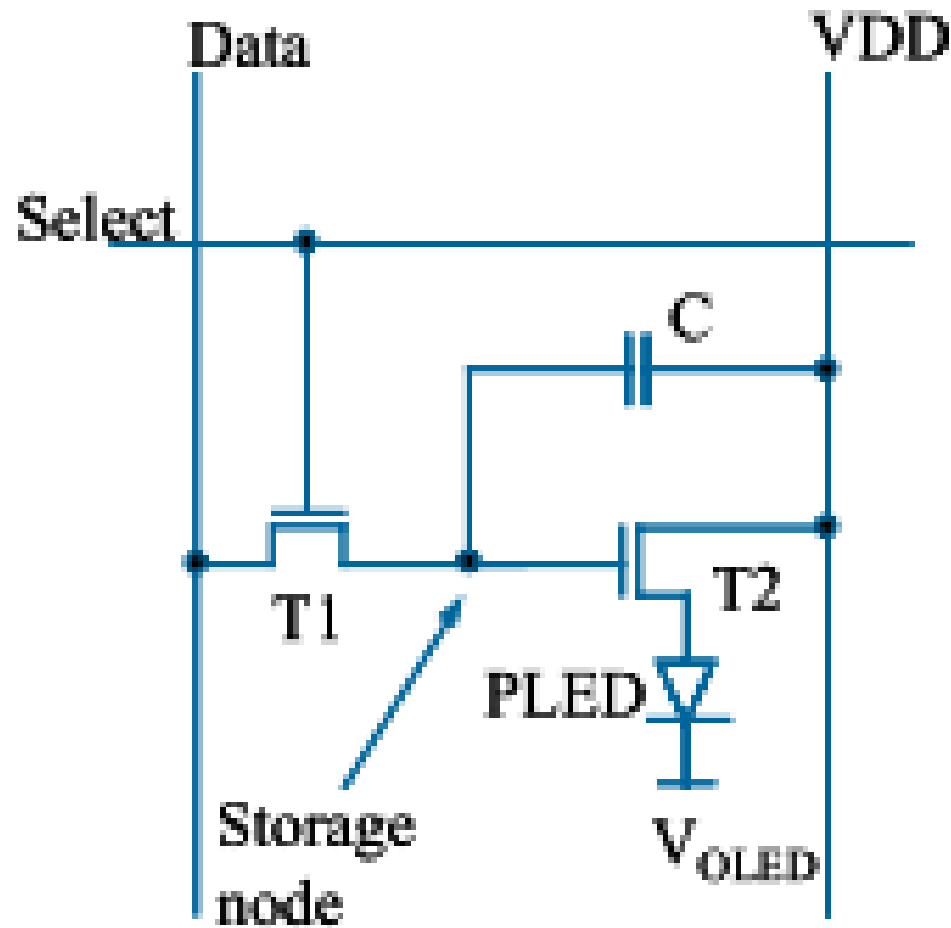
- Fator de modulação de corrente (relação *on/off*);
- Tensão de inversão (*Threshold voltage*);
- Mobilidade dos portadores majoritários;
- *Off current (leakage + intrinsic conduction)*;

# TFTs in active-matrix display circuits

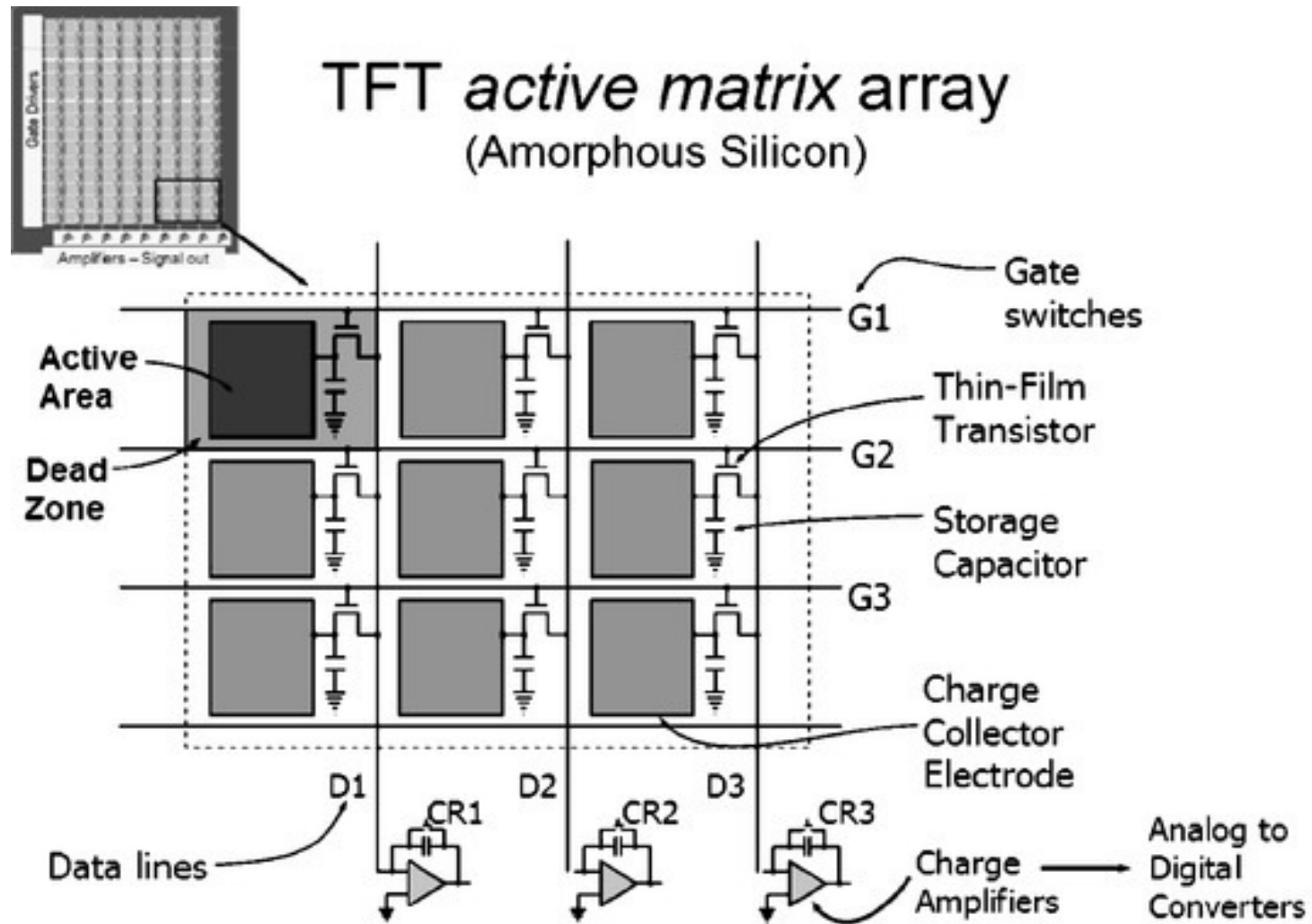


# TFTs em circuitos de matriz ativa

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# TFTs em circuitos de matriz ativa



# TFTs in active-matrix display circuits

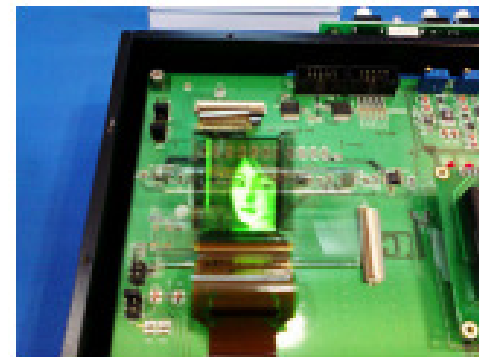
**Flexible BW E-paper  
5.35",VGA,150ppi  
(Toppan, 2009)**



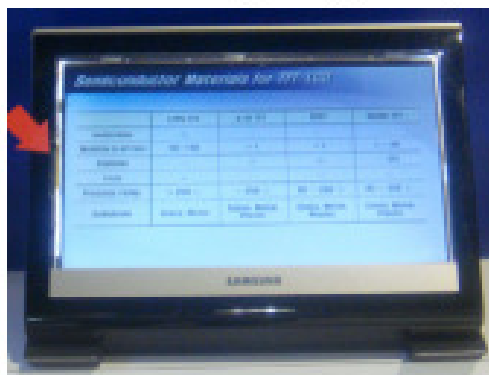
**Flexible BW E-paper  
2",VGA,400ppi  
(Toppan, 2009)**



**Scan-driver-integrated  
AM-OLED  
(LGE&ETRI,2009)**



**Gate-driver-integrated  
15" WXGA AM-LCD  
1280×720 (SEC, 2008)**



**19" QFHD AM-OLED  
960×540 (SMD, 2009)**



**37" FHD AM-LCD  
1920×1080  
(AUO, 2010)**



# TFTs in active-matrix display circuits

Hi-Res LCD  
Smart Phones  
(2010-)



iPhone 4 & 5

Hi-Res LCD & OLED Tablets  
(2012-)



New iPad



Samsung  
Galaxy OLED

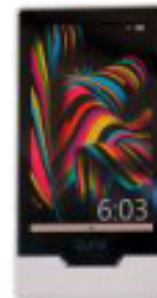
OLED Smart Phones (2010-)



Google  
Nexus One



Samsung  
Galaxy SII



Microsoft  
Zune



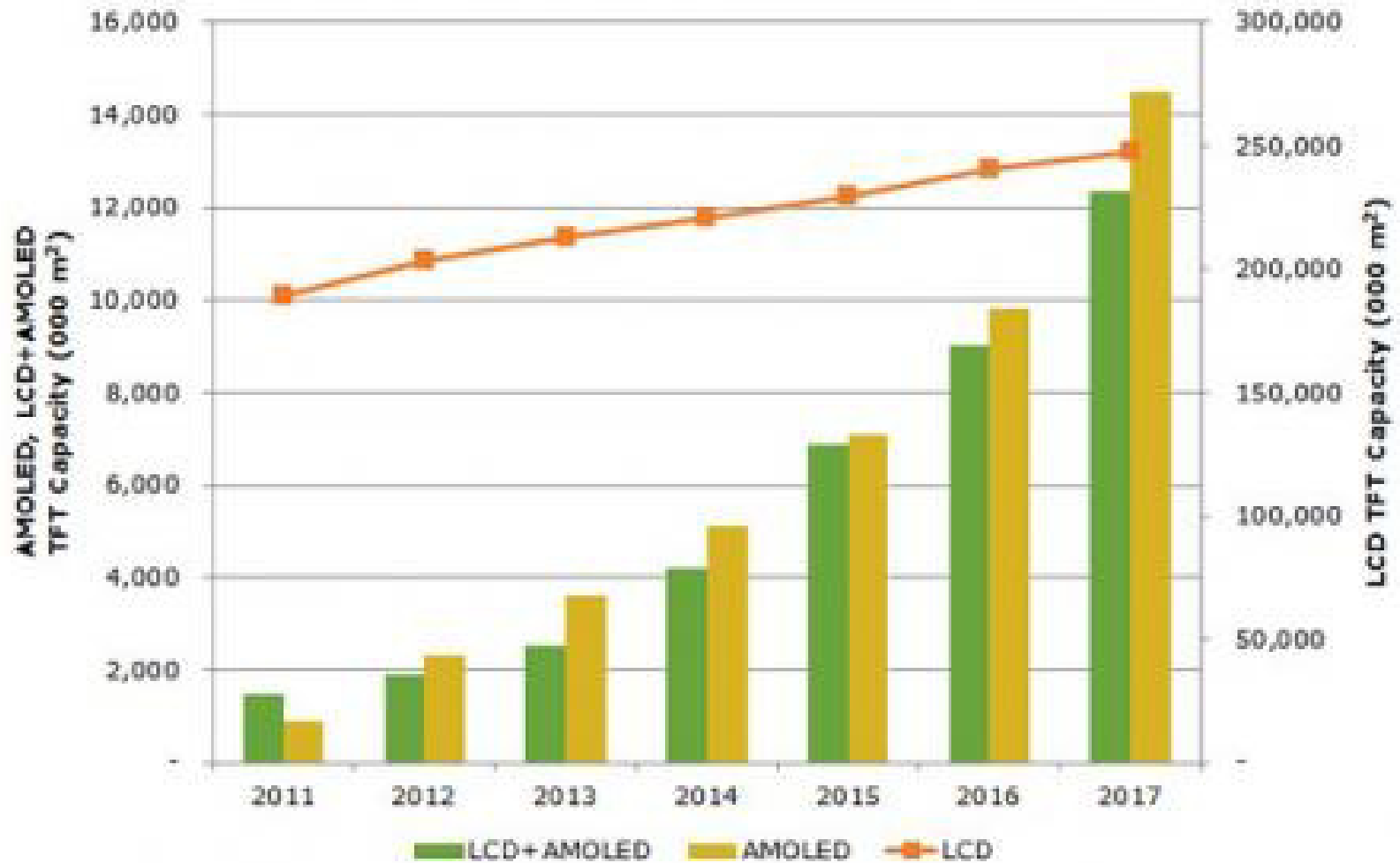
# TFTs in active-matrix display circuits



# TFTs in active-matrix display circuits

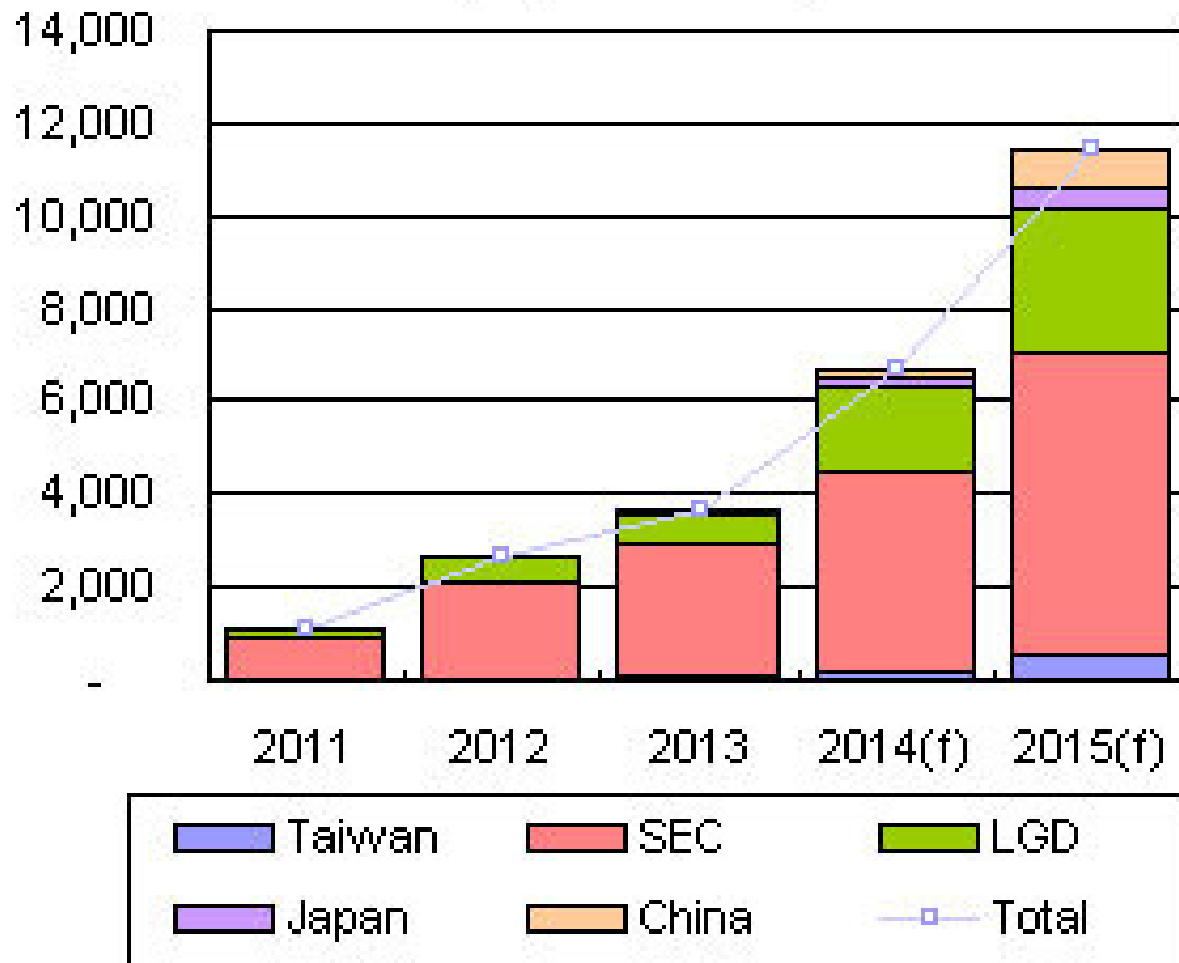
- **Current demand:**
  - high mobility (higher scan rates);
  - transparency;
  - flexibility;
  - low production cost;
  - large areas;

# Production of AM-displays

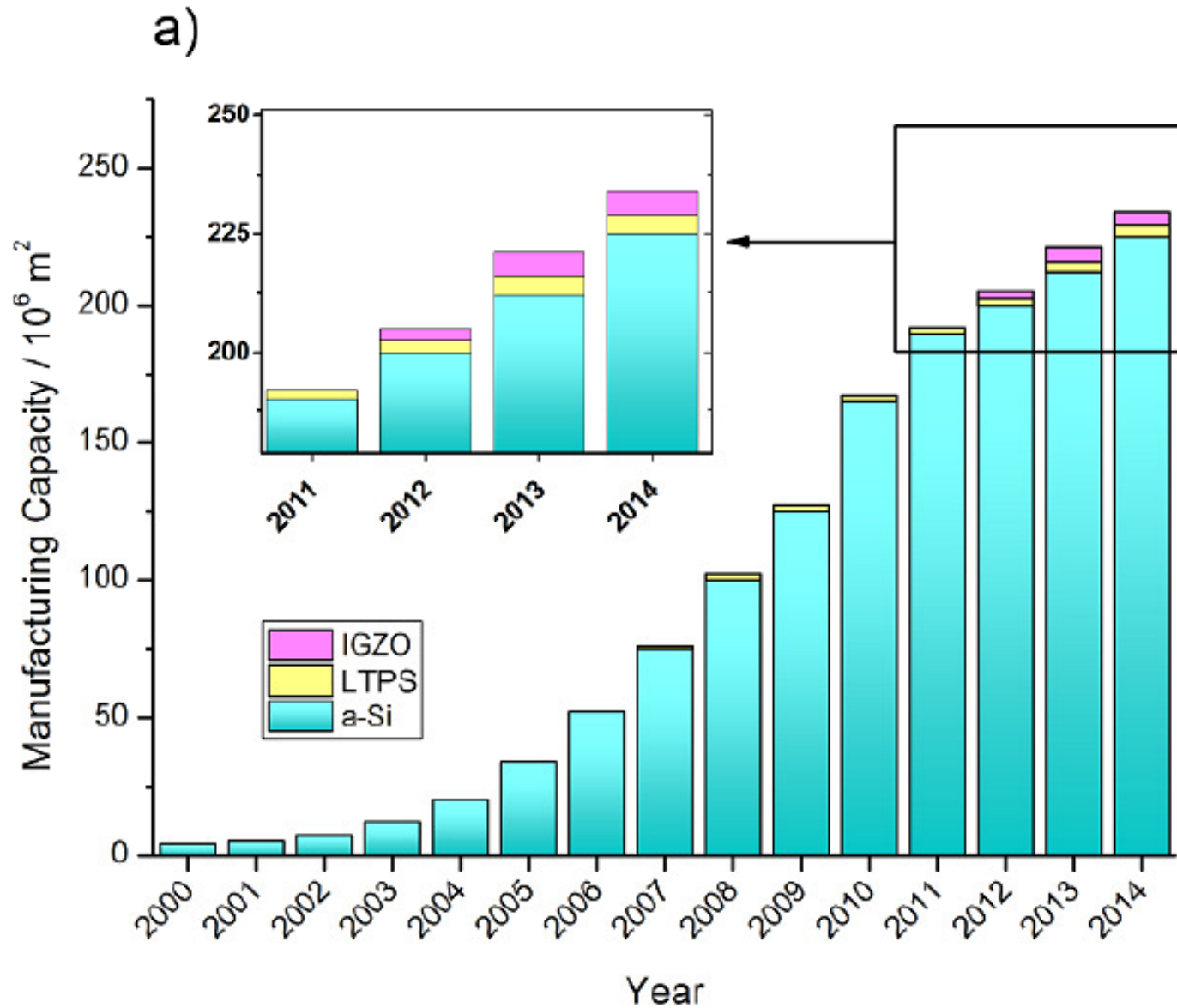


# Capacidade de produção de AM-displays

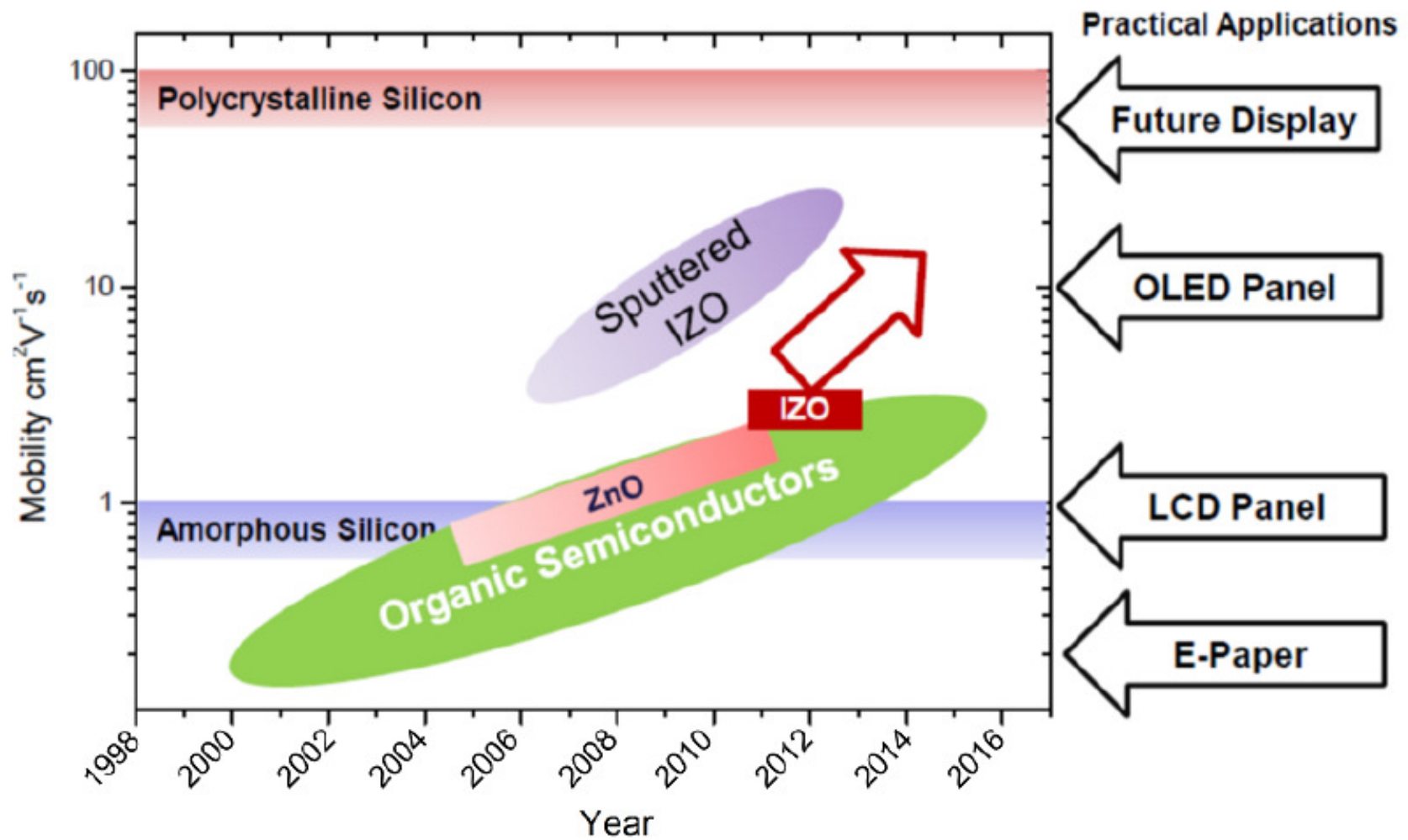
Global AMOLED panel capacity, 2011-2015  
(k square meters)



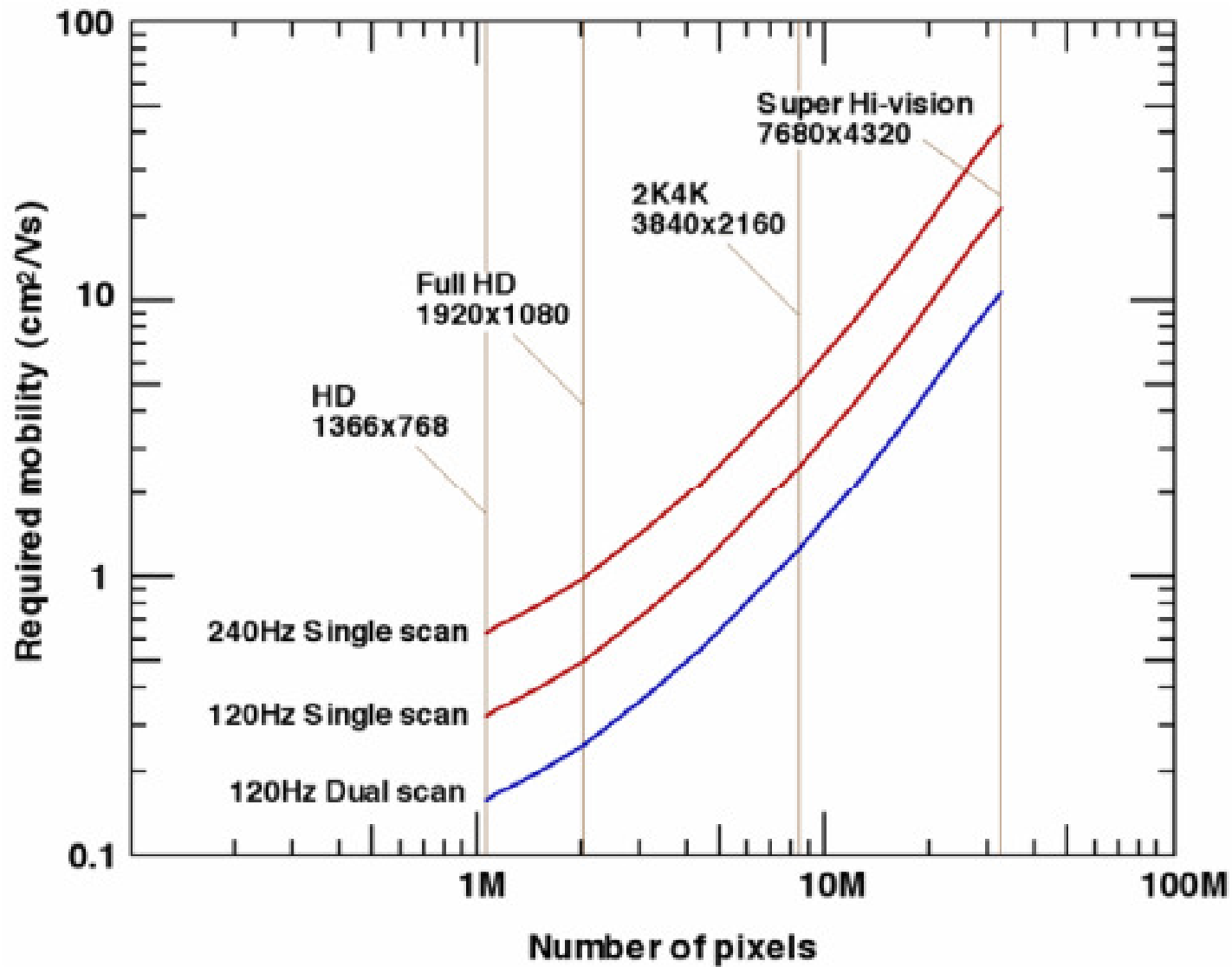
# Production of AM-displays



# Production of AM-displays



# Demand for higher mobilities

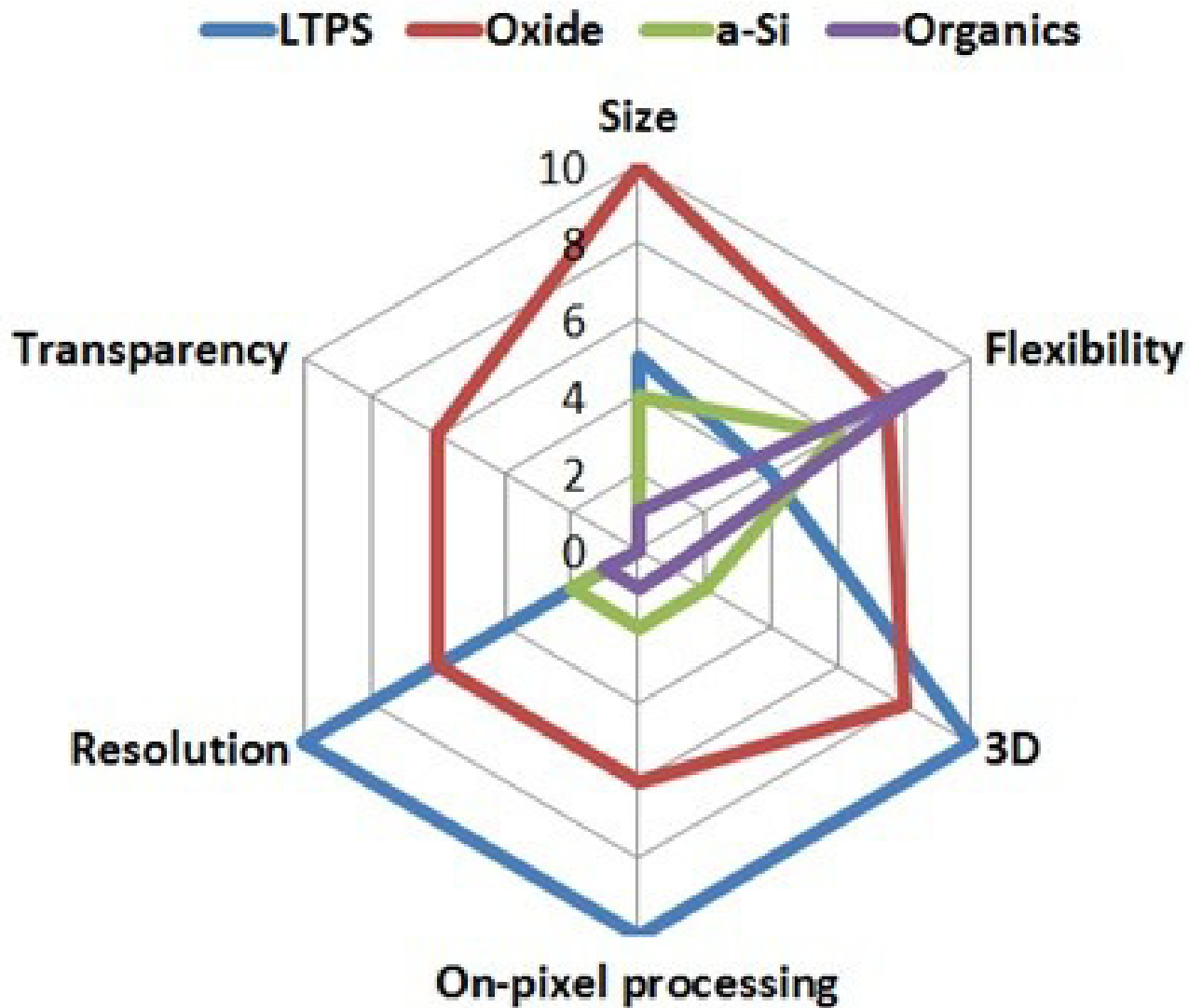


# Comparison among different technologies

- **Low-temperature polycrystalline silicon (LTPS):**
  - Liquid-phase chemical vapour deposition (LPCVD), plasma-enhanced chemical vapour deposition (PECVD), or solid-phase crystallization (SPC). Temperatures usually higher than 500°C; High mobility; Non-uniform films; Not suitable for large areas;
- **Amorphous Metal-Oxide semiconductors (AMOS):**
  - Deposited by RF-sputtering, pulsed-laser deposition (PLD) or solution processed organic precursor pyrolysis; Suitable for large areas; Suitable for transparent applications; Suitable for flexible applications;
- **Amorphous Silicon (a-Si):**
  - Deposited by Chemical-vapour deposition (CVD), Physical-vapour deposition (PVD); Suitable for flexible applications;
- **Organic Semiconductors (OS):**
  - Deposited by spin-coating, physical vapour deposition, ink-jet printing; Suitable for flexible applications;



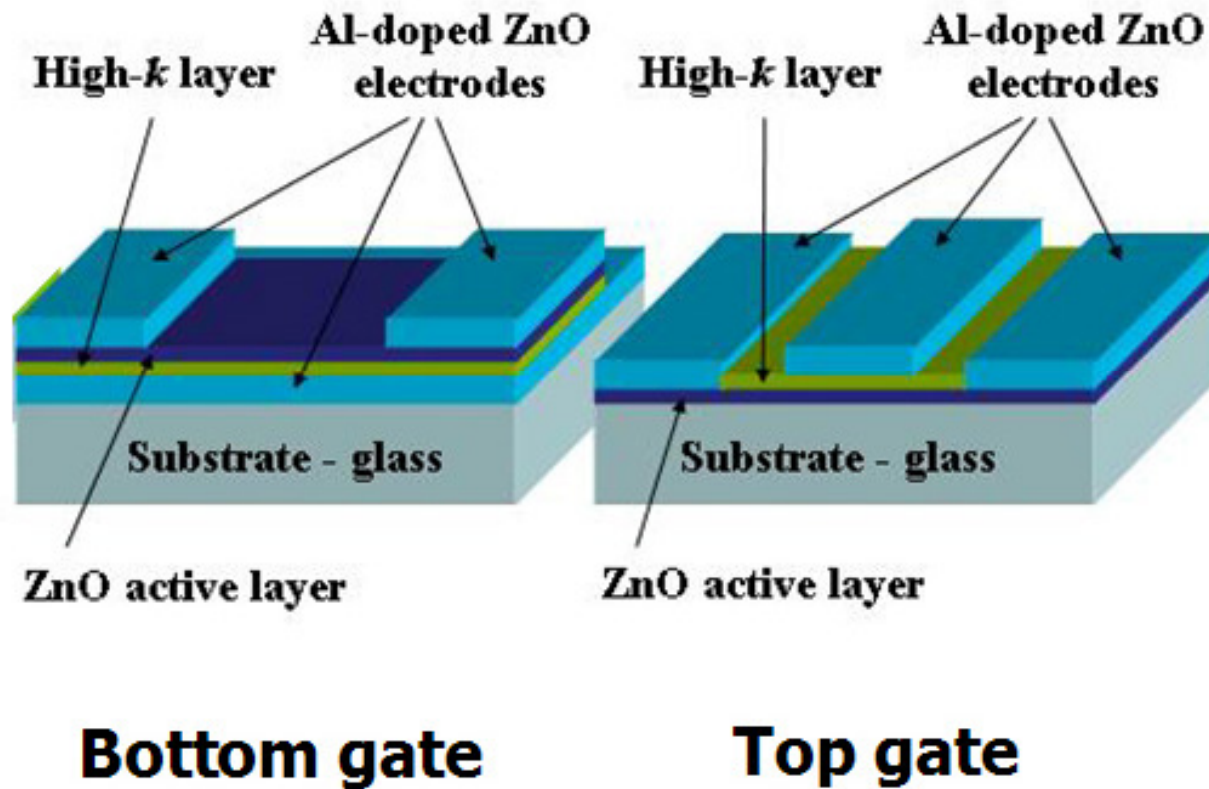
# Comparison among different technologies



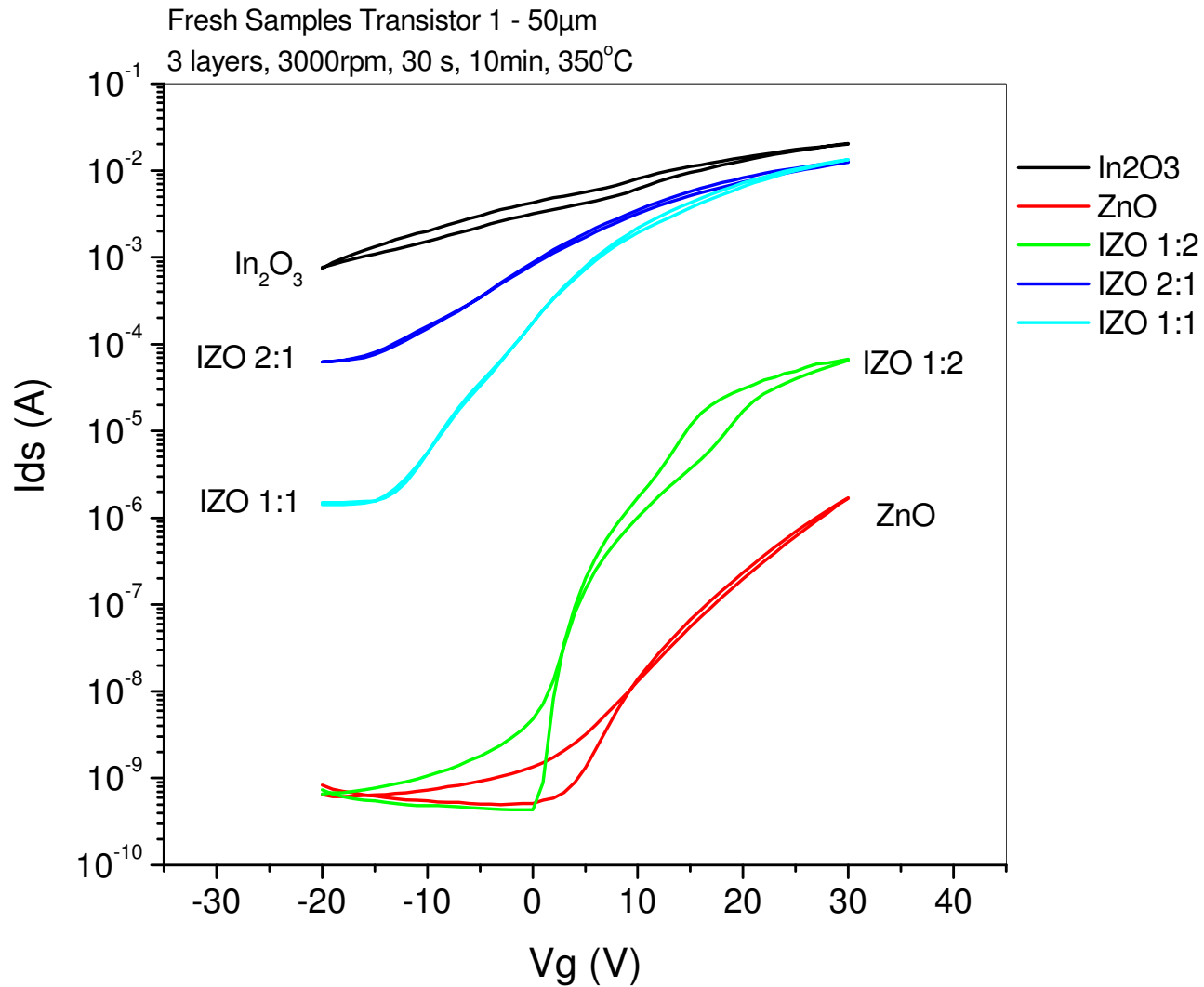
# Amorphous metal-oxide TFTs

- Why using AMO TFTs ?
- Advantages:
  - Low-cost and easy processing;
  - higher mobilities ( $1\text{-}20\text{cm}^2\cdot\text{V}^{-1}\text{s}^{-1}$ ) compared to a-Si and more uniform films than poly-Si;
  - Highly transparent in the whole visible spectrum;
  - Can be solution-processed (spin-coating, dip-coating, ink-jet printing, spray deposition);
- Disadvantages :
  - Processing temperatures are still relatively high ( $\sim 350^\circ\text{C}$ ) to enable flexible substrate deposition.

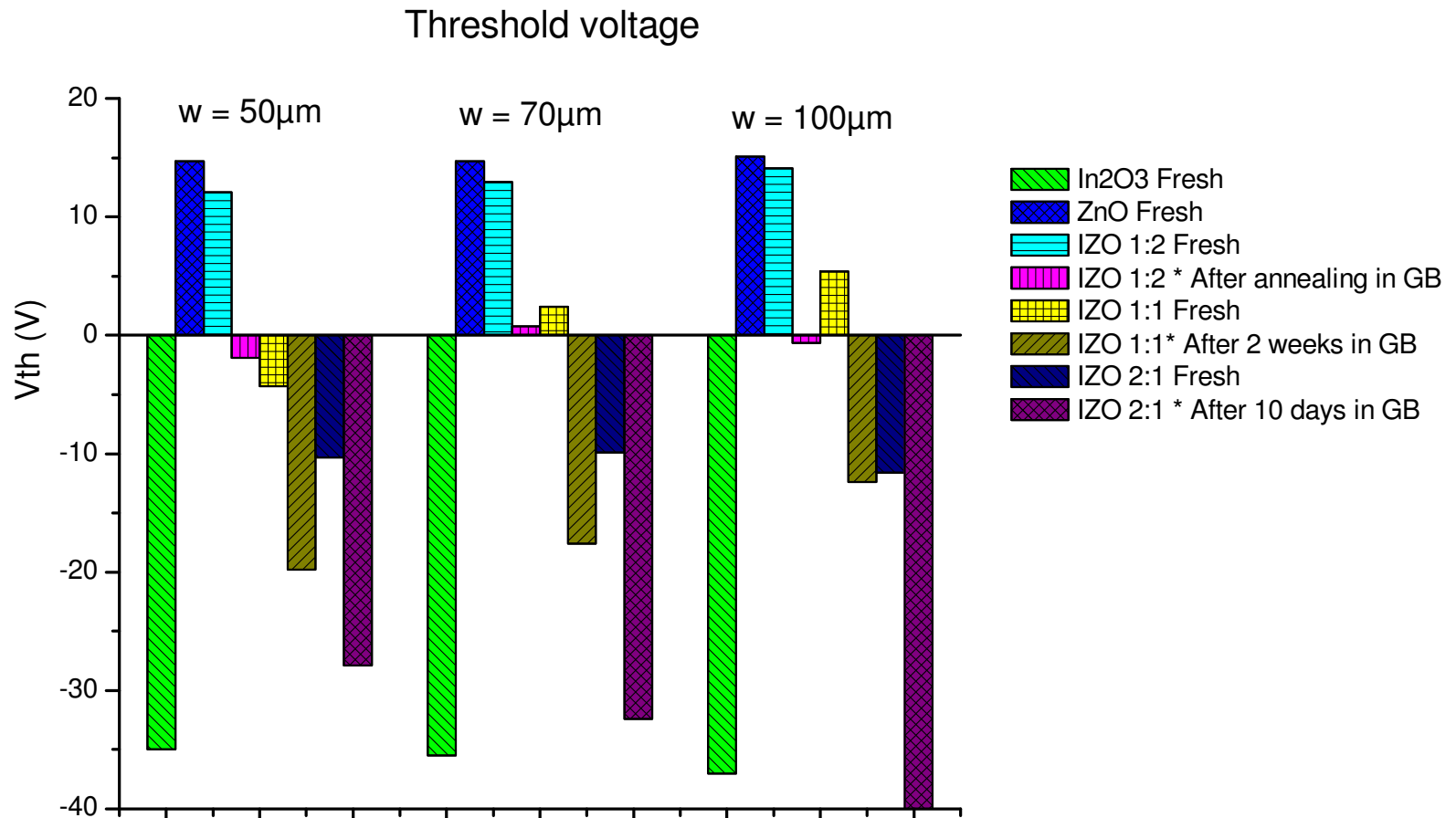
# Transistores de Óxidos metálicos amorfos (AMOs)



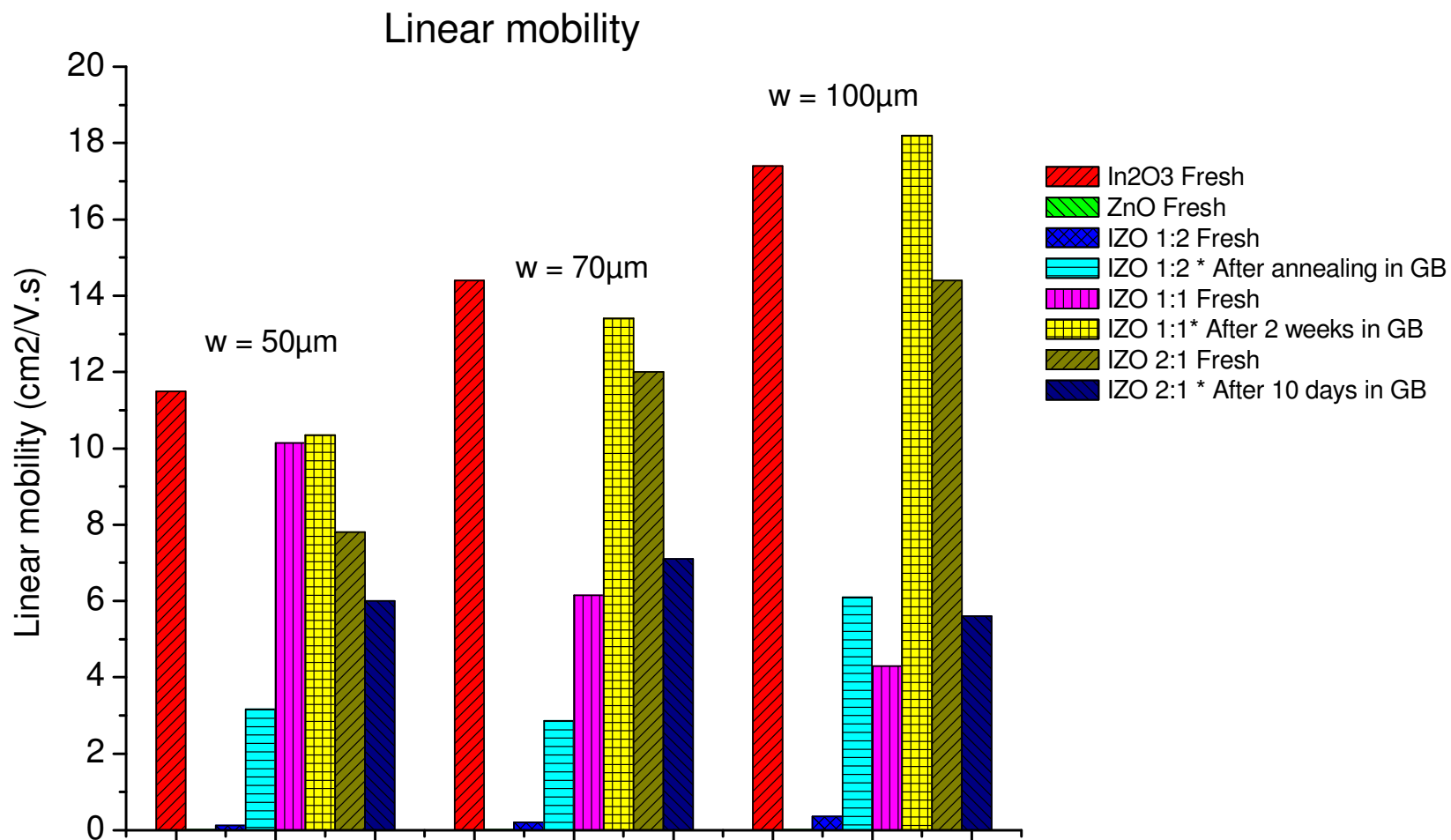
# Amorphous metal-oxide TFTs



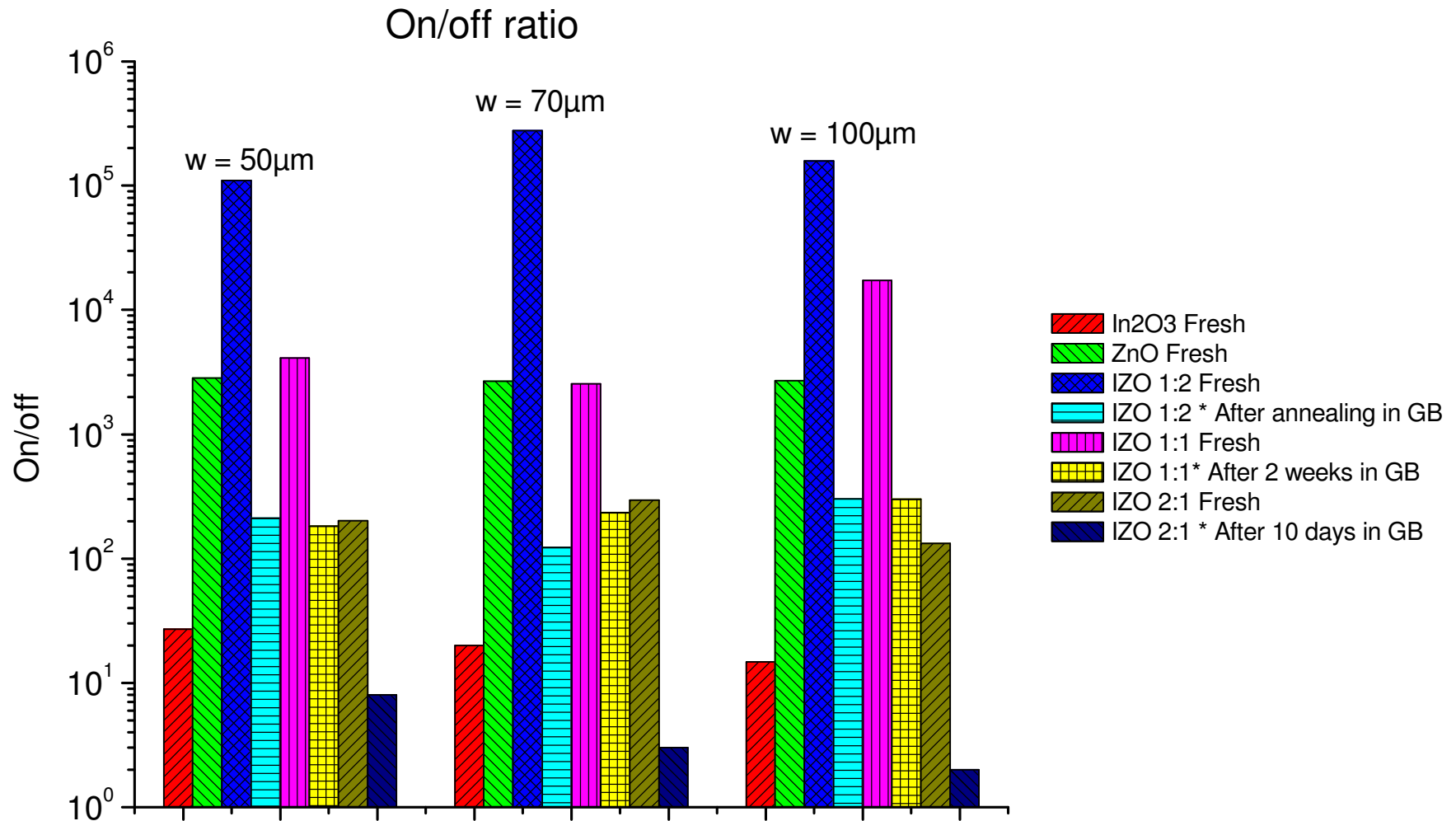
# Solution-processed AMO-TFTs



# Solution-processed AMO-TFTs



# Solution-processed AMO-TFTs



## Conclusions and Perspectives

- Solution-processed AMOs can achieve high enough mobilities for application in drive circuits of high-resolution active-matrix displays;
- There are still lots of open questions concerning device stability and the role of oxygen on the electrical properties of TFTs active layers;
- Morphology and growth dynamic can affect the device performance. Better control of deposition parameters;
- Processing temperature has to be lowered to enable flexible applications;



# Grupo de Optoeletrônica Orgânica - UNESP

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Thank you for your attention!